

PATENT
99-CT-371/DP2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Michele VULPIO

: Group Art Unit: 1734

Serial No.: 10/693,639

Filed: October 24, 2003

: Confirmation No.: 8902

For: METHOD OF USING SACVD
DEPOSITION AND CORRESPONDING
DEPOSITION REACTORINFORMATION DISCLOSURE STATEMENTCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The attached Form PTO-1449 provides a listing of information which may be relevant to the subject application. This IDS is not intended as a representation that better art is not available, nor that other art than that identified exists; nor that the information provided is prior art; nor that a search has been made.

This IDS is submitted under:

- ☒ XX 37 CFR 1.97(b) - No Fee.
☐ 37 CFR 1.97(c) - No Fee, with Certification.
☐ 37 CFR 1.97(c) - Fee.
☐ 37 CFR 1.97(d) - Fee and Certification.

The Commissioner is authorized to charge any required fees under 37 CFR 1.17(p) and (i)(1) to Deposit Account No. 50-1556.

Respectfully submitted,

Date: 7/29/04By: [Signature]Stephen Bongini
Registration No. 40,917FLEIT, KAIN, GIBBONS,
GUTMAN, BONGINI & BIANCO P.L.
551 NW 77th Street, Suite 111
Boca Raton, Florida 33487
Telephone: (561) 989-9811
Facsimile : (561) 989-9812**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service by first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Kathleen Schlosdon
Name of Person Mailing PaperKathleen Schlosdon
Signature of Person Mailing Paper7/29/04
Date of Deposit

AUG 03 2004

Form PTO-1449	U.S. Dept. of Commerce Patent & Trademark Office	Atty. Docket No. 99-CT-371/DP2	Serial No. 10/693,639
List of Documents Cited by Applicant (Use several sheets if necessary)		Applicant: Michele VULPIO	
		Filing Date: October 24, 2003	Group: 1734

U.S. PATENT DOCUMENTS

Ex'rs In'l		Document Number	Date	Name	Class	Sub- class	Filing Date, if applicable
	AA1	5,356,477	October 18, 1994	Visser.			
	AA2	5,324,690	June 28, 1994	Gelatos et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub- class	Trans'l'n Yes/No
	AA3	0 299 249	January 18, 1989	Europe			Yes

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	AA4	Raupp, G. B. et al. "Conformality of SiO ₂ sub 2/films from tetraethoxysilane-sourced remote microwave plasma-enhanced chemical vapor deposition", <i>Journal of Vacuum Science and Technology (Vacuum, Surfaces and Films)</i> , May-June 1995 pp. 676-680, XP002143946.
	AA5	European Search Report for European Patent Application No. 00830153.3. dated July 31, 2001.

Examiner:	Date Considered:
-----------	------------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.